

**Reply Under 37 C.F.R. § 1.116
Expedited Procedure
Technology Center 1700**

Attorney Docket No. 740756-2709

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)	
Koichiro TANAKA)	Confirmation No. 9528
Application No. 10/769,820)	Examiner: Samuel Heinrich
Filed: February 3, 2004)	Group Art Unit: 1793
For: LASER IRRADIATION STAGE,)	
LASER IRRADIATION OPTICAL)	
SYSTEM, LASER IRRADIATION)	
APPARATUS, LASER IRRADIATION)	
METHOD, AND METHOD OF)	
MANUFACTURING A)	
SEMICONDUCTOR DEVICE)	

AMENDMENT WITH RCE

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Final Office Action mailed December 28, 2007, and together with the Request for Continued Examination concurrently filed herewith, please amend the above-identified application as follows: